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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Chen-Chung Li Group Art Unit: 2881
Serial No.: 10/804,890 Examiner: Souw, Bernard E.
Filed: March 18, 2004 In Response to Office Action
Dated: December 1, 2004

For: ION IMPLANTER AND METHOD OF PREVENTING UNDESIRABLE IONS FROM
IMPLANTING A TARGET WAFER

Attorney Docket No.: 67,200-1218

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service first class mail in an envelope addressed to Mail Stop: Fee Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

Date: Apr. 1, 2005


Kathy Dixon

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT/RESPONSE UNDER 37 C.F.R. §1.111

Dear Sir:

In response to the Office Action of December 1, 2004, please amend the above-identified application as follows:

Amendments to the Specification: begin on page 2 of this paper
Amendments to the Claims are reflected in the listing of claims that begins on page 5 of this paper.

Amendments to the Drawings begin on page 13 of this paper and include both an attached replacement sheet and an annotated sheet showing changes.

Remarks/Arguments begin on page 14 of this paper.

Two Credit Card Payment Forms are attached herewith in the amount of \$200.00 for one additional independent claim and \$120.00 for a one-month Extension of Time.

04/07/2005 CCHAU1 00000016 10804890

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